Marcel Melzer

List of Publications by Year
in descending order

12 papers	89 citations	1684188 5 h-index	1588992 8 g-index
12 all docs	12 docs citations	12 times ranked	113 citing authors

#	Article	IF	Citations
1	Static High Voltage Actuation of Piezoelectric AlN and AlScN Based Scanning Micromirrors. Micromachines, 2022, 13, 625.	2.9	2
2	Piezoelectric Scanning Micromirror With Built-In Sensors Based on Thin Film Aluminum Nitride. IEEE Sensors Journal, 2021, 21, 9682-9689.	4.7	20
3	Design and technology for uniform aluminum nitride piezoelectric micromachined ultrasonic transducers with radial array. , 2021, , .		1
4	2D Scanning Micromirror with Large Scan Angle and Monolithically Integrated Angle Sensors Based on Piezoelectric Thin Film Aluminum Nitride. Sensors, 2020, 20, 6599.	3.8	17
5	On the relationship between SiF4 plasma species and sample properties in ultra low-k etching processes. AIP Advances, 2020, 10, .	1.3	1
6	Ruthenium(II) MOCVD Precursors for Phosphorusâ€Doped Ruthenium Layer Formation. European Journal of Inorganic Chemistry, 2020, 2020, 1612-1623.	2.0	2
7	Piezoelectric Scanning Micromirror with Large Scan Angle Based on Thin Film Aluminum Nitride. , 2019, , .		9
8	Piezoelectric scanning micromirror with built-in sensors based on thin film aluminum nitride. , 2019, , .		4
9	Thin Film Piezoelectric Aluminum Nitride for Piezoelectric Micromachined Ultrasonic Transducers. , 2018, , .		3
10	Low-temperature chemical vapor deposition of cobalt oxide thin films from a dicobaltatetrahedrane precursor. RSC Advances, 2017, 7, 50269-50278.	3.6	15
11	Chemical vapor deposition of ruthenium-based layers by a single-source approach. Journal of Materials Chemistry C, 2016, 4, 2319-2328.	5.5	6
12	Copper oxide atomic layer deposition on thermally pretreated multi-walled carbon nanotubes for interconnect applications. Microelectronic Engineering, 2013, 107, 223-228.	2.4	9